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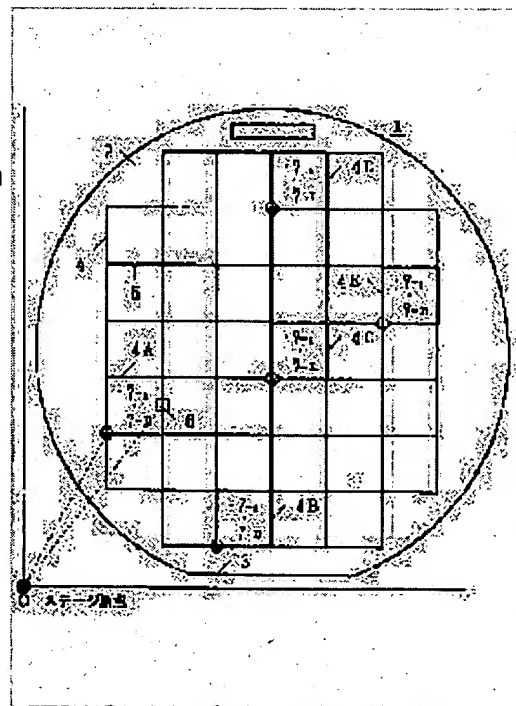
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## (54) PATTERN INSPECTION OF SEMICONDUCTOR WAFER

### (57)Abstract:

**PURPOSE:** To automatically quickly search and align identifiers(ID), by a method wherein, after a reference indicator of simple shape which is previously formed on a semiconductor wafer is detected, each position of the identifiers is specified on the basis of the positions of the reference indicator.

**CONSTITUTION:** An inspection condition file and a kind condition file are recorded on the storage device of an ID reader. When inspection work is performed, a target 6 wherein the shape is simple and the contrast is good is detected. On the basis of the position of the target mark 6, ID7-1-7-n as inspection objects are detected, and reading work and recognition work are progressed in order. Each is specified and aligned. Thereby ID can be accurately and quickly detected, and the detection ratio about indicator groups of objects to be inspected can be remarkably improved.



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